



## Metrology at High-Power Laser Facilities: Primary and Secondary Laser-Driven Sources

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### Message from the Guest Editors

Dear Colleagues,

The development of chirped pulse amplification for ultrashort laser pulses made possible the production of extreme light intensities and subsequently enabled the investigation of a plethora of new processes.

The scientific community is now facing a transition phase, from laboratory to facility-grade laser-driven sources. This requires the harmonization of the metrology for laser-driven primary and secondary sources across the facilities, as a central request of the lasers scientific community and of the non-specialist beamtime beneficiaries at these facilities.

We are inviting the scientific community to contribute research articles and review papers engaging in laser and laser-driven sources metrology. Research areas may include (but are not limited to) metrology subjects related to primary and secondary sources at laser facilities:

- pulse sampling
- review of metrology procedures and technologies
- new instrumentation for metrology
- indirect characterization of extreme light-driven sources through experiments

We look forward to receiving your contributions.

